

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Conf. No. 8417

Nobuhiro Miki, et al.

Application No.: 10/656,190

Group Art Unit: 1746

Filed: September 8, 2003

Examiner: Michail Kornakov

For: SURFACE PURIFICATION APPARATUS
AND SURFACE PURIFICATION METHOD

AMENDMENT

MS Amendment

Commissioner for Patents
Washington, DC 20231

Dear Sir:

INTRODUCTORY COMMENTS

In response to the Office Action mailed on December 6, 2006, please amend the above-identified U.S. patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.